



Nanostructured Photovoltaic Devices, Volume II

Guest Editor:

Dr. Ruxandra Vidu

1. Electrical Engineering and
Computer Science, University of
California Davis, Davis, CA 95616,
USA

2. Faculty of Material Sciences
and Engineering, Politehnica
University of Bucharest, 060042
Bucharest, Romania

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Message from the Guest Editor

The search for new materials, new processes, and new material designs for high-efficiency light harvesting, trapping, and conversion to electricity has become the biggest challenge of the century. Synergistic relationships between materials science, chemistry, physics, electric, electronic, and optics have contributed to the extraordinary growth in the field of nanomaterials for photovoltaic applications. In particular, nanostructured photovoltaics have already proven to represent rapid developments and are marked to revolutionize our everyday life. The exciting developments in the field of the light trapping features of nanostructures and solar cell nano-engineered architecture present challenges with unique opportunities to explore new ideas regarding nanostructure integration into photovoltaics.





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Editor-in-Chief

Prof. Dr. Ai-Qun Liu

1. Department of Electrical and Electronic Engineering, The Hong Kong Polytechnic University, Hong Kong, China
2. School of Electrical and Electronic Engineering, Nanyang Technological University, Singapore 639798, Singapore

Message from the Editor-in-Chief

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Micromachines Editorial Office
MDPI, Grosspeteranlage 5
4052 Basel, Switzerland

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